

PATENT NUMBER

U.S. UTILITY Patent Application

O.J.P.E.

PATENT DATE

SCANNED 1 11

APPLICATION NO.
09/988302

CONT/PRIOR
F

CLASS
134

SUBCLASS

ART UNIT
1710

EXAMINER Winter

APPLICANTS

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Sung Hwang

TITLE

Cleaning apparatus of a high density plasma chemical vapor deposition chamber and cleaning method thereof

PTO-2040
12/99

ISSUING CLASSIFICATION

ORIGINAL			CROSS REFERENCE(S)							
CLASS		SUBCLASS	CLASS	SUBCLASS (ONE SUBCLASS PER BLOCK)						
INTERNATIONAL CLASSIFICATION										

☐ Continued on Issue Slip Inside File Jacket

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**TERMINAL
DISCLAIMER**

☐ The term of this patent subsequent to _____ (date) has been disclaimed.

☐ The term of this patent shall not extend beyond the expiration date of U.S. Patent No. _____

☐ The terminal ____ months of this patent have been disclaimed

DRAWINGS

Sheets Drwg.

Figs. Drwg.

Print Fig.

(Assistant Examiner)

(Date)

(Primary Examiner)

2. 代理權

(Legal Instruments Examiner)

(Distance)

CLAIMS ALLOWED

Total Claims

Print Claim for O.G.

NOTICE OF ALLOWANCE MAILED

ISSUE FEE

Amount Due

Date Paid

ISSUE BATCH NUMBER

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(FACE)